

What is claimed is:

1. A method of forming a thin film,
wherein a sample boat having an EL material contained therein, a substrate having an electrode provided thereon, and a mask between the sample boat and the substrate are provided,
wherein the EL material is made to be in a vapor state in the sample boat,
wherein the EL material in the vapor state is discharged from the sample boat toward the substrate, and
wherein the EL material in the vapor state is made to pass through an opening of the mask corresponding to the electrode to deposit the EL material on the electrode on the substrate and form a thin film.
2. A method of forming a thin film as claimed in claim 1, wherein voltage is applied to the mask.
3. A method of forming a thin film as claimed in claim 1, wherein the EL material in a vapor state is charged when the EL material is made to be in a vapor state in the sample boat and the EL material in a vapor state is discharged from the sample boat toward the substrate.
4. A method of forming a thin film as claimed in claims 1, wherein the opening in the mask is a gap of blocking portions.
5. A method of forming a thin film as claimed in claim 1, wherein there are a plurality of the masks and different voltages are applied to the respective plurality of masks.
6. A method of forming a thin film as claimed in claim 1, wherein the electrode is a pixel electrode.
7. A method of forming a thin film as claimed in claim 1, wherein the EL material is a low molecular weight material.
8. A method of forming a thin film as claimed in claim 1, wherein the thickness of the thin film is 10 nm to 10 μm .

9. A method of forming a thin film as claimed in claim 1, wherein the mask is a conductive wire formed of a conductive material, a mesh-like structure formed of conductive wires, a plate-like structure formed of a conductive material, or a plurality of conductive wires arranged in parallel with one another.

10. A self-light-emitting device manufactured using a method of forming a thin film as claimed in claim 1.

11. A thin film forming device comprising:

- a sample boat having an EL material contained therein;
- means for making the EL material in a vapor state in the sample boat;
- a substrate having an electrode provided thereon;
- a mask between the sample boat and the substrate; and
- means for applying voltage to the mask.

12. A thin film forming device as claimed in claim 11, wherein a direction of progress or a location of deposition of the EL material in the vapor state is controlled by the means for applying voltage to the mask.

13. A thin film forming device as claimed in claim 11, further comprising means for charging the EL material in the vapor state.

14. A thin film forming device as claimed in claim 11, by further comprising another mask provided between the substrate and the mask, and voltage which is different from that applied to the mask is applied to the another mask .

15. A method of forming a thin film,

- wherein a sample boat having an EL material contained therein, a substrate having an electrode provided thereon, and a mask between the sample boat and the substrate are provided.

- wherein the EL material is made to be in a vapor state in the sample boat,

- wherein the EL material in the vapor state is discharged from the sample boat toward the substrate,

wherein the EL material in the vapor state is made to pass through an opening of the mask corresponding to the electrode to deposit the EL material on the electrode on the substrate and form a thin film, and

wherein voltage is applied to the mask.

16. A method of forming a thin film,

wherein a sample boat having an EL material contained therein, a substrate having an electrode provided thereon, and a mask between the sample boat and the substrate are provided,

wherein the EL material is made to be in a vapor state in the sample boat,

wherein the EL material in the vapor state is discharged from the sample boat toward the substrate,

wherein the EL material in the vapor state is made to pass through an opening of the mask corresponding to the electrode to deposit the EL material on the electrode on the substrate and form a thin film, and

wherein the EL material in the vapor state is charged.

17. A thin film forming device comprising:

a sample boat having an EL material contained therein;

means for making the EL material in a vapor state in the sample boat;

a substrate having an electrode provided thereon;

a mask between the sample boat and the substrate;

means for applying voltage to the mask; and

means for charging the EL material in the vapor state.